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PALM INTRANET**Inventor Name Search Result**

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Last Name = KANAI

First Name = MASAHIRO

Application#	Patent#	Status	Date Filed	Title	Inventor Name 51
60381442	Not Issued	159	05/17/2002	METHOD AND APPARATUS FOR PACKAGING LIGHTWEIGHT OBJECTS	KANAI, MASAHIRO
10779683	Not Issued	019	02/18/2004	NONVOLATILE SEMICONDUCTOR MEMORY DEVICE	KANAI, MASAHIRO
10776173	Not Issued	020	02/12/2004	PROCESSING APPARATUS, EXHAUST PROCESSING PROCESS AND PLASMA PROCESSING PROCESS	KANAI, MASAHIRO
10763126	Not Issued	019	01/22/2004	IMAGE PROCESSING DEVICE, IMAGE PROCESSING METHOD AND SOLID-STATE IMAGE-PICKUP DEVICE	KANAI, MASAHIRO
10763122	Not Issued	019	01/22/2004	IMAGE PROCESSING DEVICE, IMAGE PROCESSING METHOD AND SOLID-STATE IMAGE-PICKUP DEVICE	KANAI, MASAHIRO
10745604	Not Issued	020	12/29/2003 1181-1163	PLASMA-PROCESSING APPARATUS	KANAI, MASAHIRO JFW
10733455	Not Issued	030	12/12/2003	NON-VOLATILE MEMORY DEVICE	KANAI, MASAHIRO
10733452	Not Issued	030	12/12/2003	DEPOSITED-FILM FORMATION APPARATUS, AND DEPOSITED-FILM FORMATION PROCESS	KANAI, MASAHIRO
10656131	Not Issued	020	09/08/2003	DEPOSITED FILM FORMING APPARATUS AND DEPOSITED FILM FORMING METHOD	KANAI, MASAHIRO
10650763	Not Issued	030	08/29/2003	APPARATUS AND METHOD FOR FORMING DEPOSITED FILM	KANAI, MASAHIRO

<i>ND</i>	10650710	Not Issued	020 <i>7812</i>	08/29/2003 <i>438/38</i>	METHOD OF FORMING SILICON NITRIDE DEPOSITED FILM	KANAI, MASAHIRO <i>JFW</i>
<i>W/50</i> <i>not exp'd. no echo</i>	10625041	Not Issued	030	07/23/2003	APPARATUS FOR MANUFACTURING PHOTOVOLTAIC ELEMENTS	KANAI, MASAHIRO
<i>W/50</i> <i>not exp'd. no echo</i>	10320430 <i>2003013657</i>	Not Issued	030 <i>783</i>	12/17/2002 <i>118/724</i>	VACUUM-PROCESSING APPARATUS AND METHOD FOR VACUUM-PROCESSING AN OBJECT	KANAI, MASAHIRO <i>JFW</i>
<i>W/50</i>	10238789	Not Issued	020	09/11/2002 <i>?</i>	PRODUCTION APPARATUS OF SEMICONDUCTOR LAYER EMPLOYING DC BIAS AND VHF POWER	KANAI, MASAHIRO
<i>ND</i>	10197668	6744106	150	07/18/2002	NON-VOLATILE SEMICONDUCTOR MEMORY DEVICE	KANAI, MASAHIRO
<i>ND</i>	10197646	6654282	150	07/18/2002	NONVOLATILE SEMICONDUCTOR MEMORY DEVICE	KANAI, MASAHIRO
<i>ND</i> <i>not exp'd. limits</i>	10197643	Not Issued	041	07/18/2002	NON-VOLATILE SEMICONDUCTOR MEMORY DEVICE	KANAI, MASAHIRO
<i>ND</i>	10195543 <i>2003010623</i>	Not Issued	041 <i>753</i>	07/16/2002 <i>284/1924</i>	METHOD AND APPARATUS FOR FORMING DEPOSITION FILM, AND METHOD FOR TREATING SUBSTRATE	KANAI, MASAHIRO <i>JFW</i>
<i>ND</i>	10193066	Not Issued	061	07/12/2002	SEMICONDUCTOR DEVICE HAVING A CAPACITANCE DEVICE	KANAI, MASAHIRO
<i>ND</i>	10144720 <i>20020179012</i>	Not Issued	071 <i>783</i>	05/15/2002 <i>118/715</i>	FILM FORMING APPARATUS, ELECTRON-SOURCE MANUFACTURING APPARATUS, AND MANUFACTURING METHODS USING THE APPARATUSSES	KANAI, MASAHIRO <i>JFW</i>
<i>ND</i> <i>Cp 3,4,8 Exh never change</i>	10043601	Not Issued	095	01/09/2002	INK CARTRIDGE FOR INK-JET PRINTING APPARATUS	KANAI, MASAHIRO
<i>ND</i> <i>Cp 3,4,8 Exh never change</i>	09982846 <i>200200910815</i>	Not Issued	041 <i>2813</i>	10/22/2001 <i>438/485</i>	METHOD FOR FORMING A DEPOSITED FILM BY PLASMA CHEMICAL VAPOR DEPOSITION	KANAI, MASAHIRO <i>JFW</i>
<i>ND</i>	09955160	6587381	150	09/19/2001	PROGRAMMING METHOD FOR NON-VOLATILE SEMICONDUCTOR MEMORY	KANAI, MASAHIRO

DEVICE					
09955158	6587380	150	09/19/2001	PROGRAMMING METHOD FOR NON-VOLATILE SEMICONDUCTOR MEMORY DEVICE	KANAI, MASAHIRO
09949616	6720037	150	09/12/2001	PLASMA PROCESSING METHOD AND APPARATUS	KANAI, MASAHIRO
09912343	6472296	150	07/26/2001	FABRICATION OF PHOTOVOLTAIC CELL BY PLASMA PROCESS	KANAI, MASAHIRO
09911172	6495392	150	07/23/2001	PROCESS FOR PRODUCING A SEMICONDUCTOR DEVICE	KANAI, MASAHIRO
09900043 0020039932	Not Issued 1913	092 438/465	07/09/2001	THIN FILM FORMATION METHOD	KANAI, MASAHIRO JFW
09861520	6531654	150	05/22/2001 ?	SEMICONDUCTOR THIN-FILM FORMATION PROCESS, AND AMORPHOUS SILICON SOLAR-CELL DEVICE	KANAI, MASAHIRO
09844071	6562400	150	04/30/2001	METHOD AND APPARATUS FOR FORMING DEPOSITION FILM, AND METHOD FOR TREATING SUBSTRATE	KANAI, MASAHIRO
09818640	Not Issued	071 1963 Enc. F	03/28/2001 421/585	METHOD AND APPARATUS FOR DEPOSITED FILM	KANAI, MASAHIRO JFW
09800724	6667240	150	03/08/2001	METHOD AND APPARATUS FOR FORMING DEPOSITED FILM	KANAI, MASAHIRO
09797566	Not Issued	071	03/05/2001	APPARATUS FOR FORMING DEPOSITED FILM	KANAI, MASAHIRO
09772987	6547922	150	01/31/2001	VACUUM-PROCESSING APPARATUS AND METHOD FOR VACUUM-PROCESSING AN OBJECT	KANAI, MASAHIRO
09771650	6470823	150	01/30/2001	APPARATUS AND METHOD FOR FORMING A DEPOSITED FILM BY MEANS OF PLASMA CVD	KANAI, MASAHIRO
09769328	Not Issued	082	01/26/2001	DEPOSITED-FILM FORMATION APPARATUS, AND DEPOSITED-FILM FORMATION PROCESS	KANAI, MASAHIRO
09767856	6632284	150	01/24/2001	APPARATUS AND METHOD FOR FORMING DEPOSITED FILM	KANAI, MASAHIRO
09754258	6367920	150	01/05/2001	INK CARTRIDGE FOR INK-	KANAI,

				JET RECORDING APPARATUS, AND INK-JET RECORDING APPARATUS	MASAHIRO
09727440	6526910	150	12/04/2000	APPARATUS AND METHOD FOR FORMING A DEPOSITED FILM BY MEANS OF PLASMA CVD	KANAI, MASAHIRO
09722675	6551471	150	11/28/2000	IONIZATION FILM-FORMING METHOD AND APPARATUS	KANAI, MASAHIRO
09678299	Not Issued	161	10/03/2000	METHOD AND DEVICE FOR FORMING SEMICONDUCTOR THIN FILM AND DEVICE FOR FORMING PHOTOVOLTAIC ELEMENT	KANAI, MASAHIRO
09666182	6367502	150	09/21/2000	FLOW CONTROL DEVICE	KANAI, MASAHIRO
09664219	6368944	150	09/18/2000	METHOD OF MANUFACTURING PHOTOVOLTAIC ELEMENT AND APPARATUS THEREFOR	KANAI, MASAHIRO
09649599	6413794	150	08/29/2000	METHOD OF FORMING PHOTOVOLTAIC ELEMENT	KANAI, MASAHIRO
09645036	Not Issued	164	08/24/2000	PROCESS FOR PRODUCING A SEMICONDUCTOR DEVICE	KANAI, MASAHIRO
09625840	6447612	150	07/26/2000	FILM-FORMING APPARATUS FOR FORMING A DEPOSITED FILM ON A SUBSTRATE, AND VACUUM-PROCESSING APPARATUS AND METHOD FOR VACUUM-PROCESSING AN OBJECT	KANAI, MASAHIRO
09588626	6306267	150	06/07/2000	METHOD OF PRODUCING A PHOTOVOLTAIC DEVICE USING A SPUTTERING METHOD	KANAI, MASAHIRO
09578906	6436797	150	05/26/2000	APPARATUS AND METHOD FOR FORMING A DEPOSITED FILM ON A SUBSTRATE	KANAI, MASAHIRO
09478885	Not Issued	061	01/07/2000	APPARATUS AND METHOD FOR PROCESSING A SUBSTRATE, AND APPARATUS AND METHOD FOR FORMING A DEPOSITED FILM ON A SUBSTRATE	KANAI, MASAHIRO
09469797	6576061	150	12/22/1999	APPARATUS AND METHOD	KANAI,

				FOR PROCESSING A SUBSTRATE	MASAHIRO
09312073	Not Issued	041	05/13/1999	INK CARTRIDGE FOR INK-JET PRINTING APPARATUS	KANAI, MASAHIRO

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Your Search was:

Last Name = KANAI

First Name = MASAHIRO

Application#	Patent#	Status	Date Filed	Title	Inventor Name 51
10448112	Not Issued	030	05/30/2003	NON-VOLATILE SEMICONDUCTOR MEMORY DEVICE AND METHOD OF ACTUATING THE SAME	KANAI, MASAHIRO
10446827	Not Issued	030	05/29/2003	NON-VOLATILE SEMICONDUCTOR MEMORY DEVICE AND METHOD OF ACTUATING THE SAME	KANAI, MASAHIRO
10444990	Not Issued	030 1753	05/27/2003 2041297,01	MILLING APPARATUS 7	KANAI, MASAHIRO JFW
10425652	Not Issued	041 20030194482	04/30/2003 4271482	APPARATUS AND METHOD FOR PROCESSING A SUBSTRATE	KANAI, MASAHIRO JFW
10409190	Not Issued	030 1753	04/09/2003 20414212	METHOD OF FORMING DEPOSITED FILM	KANAI, MASAHIRO JFW
10400872	Not Issued	094 200301940412	03/28/2003 4381737	METHOD OF FORMING DEPOSITED FILM	KANAI, MASAHIRO JFW
10385506	Not Issued	030	03/12/2003	NON-VOLATILE SEMICONDUCTOR MEMORY DEVICE	KANAI, MASAHIRO
10377707	Not Issued	030	03/04/2003	NON-VOLATILE SEMICONDUCTOR MEMORY DEVICE	KANAI, MASAHIRO
10377699	6707742	150	03/04/2003	NONVOLATILE SEMICONDUCTOR MEMORY DEVICE	KANAI, MASAHIRO
10373166	Not Issued	030	02/26/2003	NONVOLATILE REGISTER AND SEMICONDUCTOR DEVICE	KANAI, MASAHIRO
10361573	Not Issued	092	02/11/2003	NONVOLATILE SEMICONDUCTOR MEMORY DEVICE	KANAI, MASAHIRO
10356644	6738291	150	02/03/2003	NONVOLATILE	KANAI,

				SEMICONDUCTOR MEMORY DEVICE	MASAHIRO
<i>no Ech</i>	<u>10350019</u> 20030743968	Not Issued	071 1818 <u>438/188</u>	01/24/2003 METHOD AND APPARATUS FOR IONIZATION FILM FORMATION	KANAI, MASAHIRO <i>IFW</i>
<i>NO</i>	<u>10346756</u>	Not Issued	030	01/17/2003 PACKAGING SYSTEM	KANAI, MASAHIRO
<i>NU</i>	<u>10193602</u>	Not Issued	061	07/12/2002 SEMICONDUCTOR DEVICE	KANAI, MASAHIRO
<i>NO</i>	<u>10157897</u>	Not Issued	030	05/31/2002 NONVOLATILE SEMICONDUCTOR STORAGE DEVICE	KANAI, MASAHIRO
<i>NO</i>	<u>10157896</u>	6707720	150	05/31/2002 NONVOLATILE SEMICONDUCTOR STORAGE DEVICE	KANAI, MASAHIRO
<i>NO Chs</i>	<u>10085102</u>	Not Issued	161 161	03/01/2002 METHOD OF MANUFACTURING PHOTOVOLTAIC ELEMENT AND APPARATUS THEREFOR	KANAI, MASAHIRO
<i>NO</i>	<u>09822191</u>	Not Issued	071	04/02/2001 EXHAUST PROCESSING METHOD, PLASMA PROCESSING METHOD AND PLASMA PROCESSING APPARATUS	KANAI, MASAHIRO
<i>NO</i>	<u>09772988</u>	6638359	150	01/31/2001 DEPOSITED FILM FORMING APPARATUS AND DEPOSITED FILM FORMING METHOD	KANAI, MASAHIRO
<i>NO</i>	<u>09772987</u>	6547922	150	01/31/2001 VACUUM-PROCESSING APPARATUS AND METHOD FOR VACUUM-PROCESSING AN OBJECT	KANAI, MASAHIRO
<i>NO</i>	<u>08923259</u>	6162988	150	09/04/1997 PHOTOVOLTAIC ELEMENT	KANAI, MASAHIRO
<i>NO</i>	<u>08416468</u>	Not Issued	166 166	04/04/1995 CONTINUOUS FORMING METHOD FOR FUNCTIONAL DEPOSITED FILMS AND DEPOSITION THEREOF	KANAI, MASAHIRO
<i>f</i>	<u>08404616</u>	Not Issued	166 166	03/15/1995 CONTINUOUS FORMING METHOD FOR FUNCTIONAL DEPOSITED FILMS AND DEPOSITION APPARATUS	KANAI, MASAHIRO
<i>f</i>	<u>08396266</u>	Not Issued	161 161	02/28/1995 PROCESS FOR FORMING DEPOSITED FILM USING A GAS PHASE METHOD INVOLVING AT LEAST ONE	KANAI, MASAHIRO

ACTIVATED COMPOUND				
08140971	Not Issued	166	10/25/1993	PROCESS FOR CONTINUOUSLY FORMING A LARGE AREA FUNCTIONAL DEPOSITED FILM BY MICROWAVE PCVD METHOD AND APPARATUS SUITABLE FOR PRACTICING THE SAME
08116547	Not Issued	161	09/07/1993	METHOD AND APPARATUS FOR CONTINUOUSLY FORMING FUNCTIONAL DEPOSITED FILMS WITH A LARGE AREA BY A MICROWAVE PLASMA CVD METHOD
08115268	Not Issued	166	09/02/1993	MICROWAVE PLASMA CVD APPARATUS WITH A DEPOSITION CHAMBER HAVING A CIRCUMFERENTIAL WALL COMPRISING A CURVED MOVING SUBSTRATE WEB AND A MICROWAVE APPLICATOR MEANS HAVING A SPECIFIC DIELECTRIC MEMBER ON THE EXTERIOR THEREOF
08104497	5366554	150	08/10/1993	DEVICE FOR FORMING A DEPOSITED FILM
08101018	Not Issued	166	08/03/1993	CONTINUOUS FORMING METHOD FOR FUNCTIONAL DEPOSITED FILMS AND DEPOSITION APPARATUS
08097046	5382531	150	07/27/1993	METHOD FOR CONTINUOUSLY MANUFACTURING A SEMICONDUCTOR DEVICE
07858410	5266116	150	03/27/1992	GLOW DISCHARGE APPARATUS FOR CONTINUOUSLY MANUFACTURING SEMICONDUCTOR DEVICE COMPRISING GAS GATES WITH SLOTTED ROLLERS
07834852	Not Issued	166	02/13/1992	PROCESS FOR CONTINUOUSLY FORMING A LARGE AREA FUNCTIONAL

				DEPOSITED FILM BY MICROWAVE PCVD METHOD AND AN APPARATUS SUITABLE FOR PRACTICING THE SAME	
07825281	5220181	150	01/15/1992	PHOTOVOLTAIC ELEMENT OF JUNCTION TYPE WITH AN ORGANIC SEMICONDUCTOR LAYER FORMED OF A POLYSILANE COMPOUND	KANAI, MASAHIRO
07515640	Not Issued	166	04/27/1990	PROCESS FOR THE FORMATION OF A POLYCRYSTALLINE SEMICONDUCTOR FILM BY MICROWAVE PLASMA CHEMICAL VAPOR DEPOSITION METHOD	KANAI, MASAHIRO
07273070	5008726	150	11/18/1988	PIN JUNCTION PHOTOVOLTAIC ELEMENT WITH P OR N-TYPE SEMICONDUCTOR LAYER COMPRISING NON-SINGLE CRYSTAL MATERIAL CONTAINING ZN, SE, TE, H IN AN AMOUNT OF 1 TO 4 ATOMIC % AND A DOPANT AND I-TYPE SEMICONDUCTOR LAYER COMPRISING NON-SINGLE CRYSTAL SI(H,F) MATERIAL	KANAI, MASAHIRO
07272926	4926229	150	11/18/1988	PIN JUNCTION PHOTOVOLTAIC ELEMENT WITH P OR N-TYPE SEMICONDUCTOR LAYER COMPRISING NON-SINGLE CRYSTAL MATERIAL CONTAINING ZN, SE, H IN AN AMOUNT OF 1 TO 4 ATOMIC % AND A DOPANT AND I-TYPE SEMICONDUCTOR LAYER COMPRISING NON-SINGLE CRYSTAL SI(H,F) MATERIAL	KANAI, MASAHIRO
07252525	4898118	150	10/03/1988	APPARATUS FOR FORMING FUNCTIONAL DEPOSITED FILM BY MICROWAVE PLASMA CVD PROCESS	KANAI, MASAHIRO
07221761	4851302	150	07/20/1988	FUNCTIONAL ZNSE:H	KANAI,

				DEPOSITED FILMS	MASAHIRO
06831704	4801468	150	02/21/1986	PROCESS FOR FORMING DEPOSITED FILM	KANAI , MASAHIRO
06831460	4778692	150	02/20/1986	PROCESS FOR FORMING DEPOSITED FILM	KANAI , MASAHIRO
06831448	4784874	150	02/20/1986	PROCESS FOR FORMING DEPOSITED FILM	KANAI , MASAHIRO
06829804	Not Issued	166	02/14/1986	PROCESS FOR FORMING DEPOSITED FILM	KANAI , MASAHIRO
06828256	4716048	150	02/11/1986	PROCESS FOR FORMING DEPOSITED FILM	KANAI , MASAHIRO
06753011	4696882	150	07/08/1985	MEMBER HAVING LIGHT RECEIVING LAYER WITH SMOOTHLY INTERCONNECTING NONPARALLEL INTERFACES	KANAI , MASAHIRO
06752920	4696881	150	07/08/1985	MEMBER HAVING LIGHT RECEIVING LAYER WITH SMOOTHLY CONNECTED INTERFACES	KANAI , MASAHIRO
06740901	4705731	150	06/03/1985	MEMBER HAVING SUBSTRATE WITH PROTRUDING SURFACE LIGHT RECEIVING LAYER OF AMORPHOUS SILICON AND SURFACE REFLECTIVE LAYER	KANAI , MASAHIRO
06725751	4705733	150	04/22/1985	MEMBER HAVING LIGHT RECEIVING LAYER AND SUBSTRATE WITH OVERLAPPING SUBPROJECTIONS	KANAI , MASAHIRO
06709888	4675263	150	03/08/1985	MEMBER HAVING SUBSTRATE AND LIGHT- RECEIVING LAYER OF A-SI:GE FILM AND A-SI FILM WITH NON-PARALLEL INTERFACE WITH SUBSTRATE	KANAI , MASAHIRO
06705516	4696884	150	02/26/1985	MEMBER HAVING PHOTOSENSITIVE LAYER WITH SERIES OF SMOOTHLY CONTINUOUS NOW- PARALLEL INTERFACES	KANAI , MASAHIRO
06632878	Not	166	07/20/1984	PHOTOCONDUCTIVE	KANAI ,

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	Issued		MEMBER	MASAHIRO
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Last Name = KANAI

First Name = MASAHIRO

Application#	Patent#	Status	Date Filed	Title	Inventor Name 51
08697783	5769963	150	08/30/1996	PHOTOVOLTAIC DEVICE	KANAI, MASAHIRO
08657066	5720826	150	05/29/1996	PHOTOVOLTAIC ELEMENT AND FABRICATION PROCESS THEREOF	KANAI, MASAHIRO
08433052	5575855	150	05/03/1995	APPARATUS FOR FORMING A DEPOSITED FILM	KANAI, MASAHIRO
08426629	5527391	150	04/21/1995	METHOD AND APPARATUS CONTINUOUSLY FORMING FUNCTIONAL DEPOSITED FILMS WITH A LARGE AREA BY A MICROWAVE PLASMA CVD METHOD	KANAI, MASAHIRO
08416468	Not Issued	166	04/04/1995	CONTINUOUS FORMING METHOD FOR FUNCTIONAL DEPOSITED FILMS AND DEPOSITION THEREOF	KANAI, MASAHIRO
07989891	Not Issued	166	12/10/1992	DEVICE FOR FORMING A DEPOSITED FILM	KANAI, MASAHIRO
07924001	Not Issued	166	11/20/1992	METHOD AND APPARATUS FOR CONTINUOUSLY FORMING A LARGE AREA FUNCTIONAL DEPOSITED FILM BY MEANS OF MICROWAVE PLASMA CVD PROCESS	KANAI, MASAHIRO
07904904	Not Issued	166	06/23/1992	PROCESS FOR FORMING DEPOSITED FILM	KANAI, MASAHIRO
07882238	5178905	150	05/08/1992	PROCESS FOR THE FORMATION OF A FUNCTIONAL DEPOSITED FILM BY HYDROGEN RADICAL-ASSISTED CVD METHOD UTILIZING	KANAI, MASAHIRO

HYDROGEN GAS PLASMA IN SHEET-LIKE STATE					
07860211	Not Issued	166	03/27/1992	DEVICE FOR FORMING A DEPOSITED FILM	KANAI, MASAHIRO
07807182	Not Issued	166	12/16/1991	METHOD AND APPARATUS FOR CONTINUOUSLY FORMING FUNCTIONAL DEPOSITED FILMS WITH A LARGE AREA BY A MICROWAVE PLASMA CVD METHOD	KANAI, MASAHIRO
07794051	Not Issued	166	11/19/1991	METHOD FOR CONTINUOUSLY FORMING A FUNCTIONAL DEPOSIT FILM OF LARGE AREA BY MICROWAVE PLASMA CVD METHOD	KANAI, MASAHIRO
07792925	Not Issued	166	11/15/1991	MICROWAVE PLASMA CVD APPARATUS WITH A DEPOSITION CHAMBER HAVING A CIRCUMFERENTIAL WALL COMPRISING A CURVED MOVING SUBSTRATE WEB AND A MICROWAVE APPLICATOR MEANS HAVING A SPECIFIC DIELECTRIC MEMBER ON THE EXTERIOR THEREOF	KANAI, MASAHIRO
07784255	Not Issued	166	10/29/1991	METHOD OF CONTINUOUSLY FORMING A LARGE AREA FUNCTIONAL DEPOSITED FILM BY MICROWAVE PCVD AND APPARATUS FOR THE SAME	KANAI, MASAHIRO
07689879	5358987	150	06/12/1992	NEW POLYSILANE COMPOSITIONS	KANAI, MASAHIRO
07685165	5244698	150	04/12/1991	PROCESS FOR FORMING DEPOSITED FILM	KANAI, MASAHIRO
07639410	5126169	150	01/10/1991	PROCESS FOR FORMING A DEPOSITED FILM FROM TWO MUTUALLY REACTIVE ACTIVE SPECIES	KANAI, MASAHIRO
07543499	5130170	150	06/26/1990	A MICROWAVE PCVD METHOD FOR CONTINUOUSLY FORMING A LARGE AREA FUNCTIONAL	KANAI, MASAHIRO

				DEPOSITED FILM USING A CURVED MOVING SUBSTRATE WEB WITH RADIATION OR PROPAGATION OF MICROWAVE ENERGY WITH A DIRECTIVITY IN ONE DIRECTION PERPENDICULAR TO THE DIRECTION OF MICROWAVE PROPAGATION	
07543431	5114770	150	06/26/1990	METHOD FOR CONTINUOUSLY FORMING FUNCTIONAL DEPOSITED FILMS WITH A LARGE AREA BY A MICROWAVE PLASMA CVD METHOD	KANAI , MASAHIRO
07542512	Not Issued	166	06/22/1990	PROCESS FOR CONTINUOUSLY FORMING A LARGE AREA FUNCTIONAL DEPOSITED FILM BY MICROWAVE PCVD METHOD AND AN APPARATUS SUITABLE FOR PRACTICING THE SAME	KANAI , MASAHIRO
07507001	5178904	150	04/10/1990	PROCESS FOR FORMING DEPOSITED FILM FROM A GROUP II THROUGH GROUP VI METAL HYDROCARBON COMPOUND	KANAI , MASAHIRO
07467540	5002617	150	01/19/1990	PIN HETEROJUNCTION PHOTOVOLTAIC ELEMENTS WITH POLYCRYSTAL AlAs (H,F) SEMICONDUCTOR FILM	KANAI , MASAHIRO
07467538	5006180	150	01/19/1990	PIN HETEROJUNCTION PHOTOVOLTAIC ELEMENTS WITH POLYCRYSTAL GAP (H,F) SEMICONDUCTOR FILM	KANAI , MASAHIRO
07467525	5002618	150	01/19/1990	PIN HETEROJUNCTION PHOTOVOLTAIC ELEMENTS WITH POLYCRYSTAL BAS (H,F) SEMICONDUCTOR FILM	KANAI , MASAHIRO
07430246	4998503	150	11/02/1989	APPARATUS FOR FORMING FUNCTIONAL DEPOSITED FILM BY MICROWAVE	KANAI , MASAHIRO

PLASMA CVD PROCESS					
07399396	4959106	150	08/28/1989	PHOTOVOLTAIC ELEMENT WITH A SEMICONDUCTOR LAYER COMPRISING NON-SINGLE CRYSTAL MATERIAL CONTAINING AT LEAST ZN, SE AND H IN AN AMOUNT OF 1 TO 4 ATOMIC %	KANAI, MASAHIRO
07354856	5038713	150	05/22/1989	MICROWAVE PLASMA TREATING APPARATUS	KANAI, MASAHIRO
07348105	Not Issued	161	04/28/1989	APPARATUS FOR FORMING DEPOSIT FILM	KANAI, MASAHIRO
07338428	Not Issued	166	04/14/1989	PROCESS FOR FORMING DEPOSITED FILM	KANAI, MASAHIRO
07302260	4914052	150	01/27/1989	PROCESS FOR THE FORMATION OF A FUNCTIONAL DEPOSITED FILM CONTAINING GROUPS III AND V ATOMS BY MICROWAVE PLASMA CHEMICAL VAPOR DEPOSITION PROCESS	KANAI, MASAHIRO
07302245	4908330	150	01/27/1989	PROCESS FOR THE FORMATION OF A FUNCTIONAL DEPOSITED FILM CONTAINING GROUP IV ATOMS OR SILICON ATOMS AND GROUP IV ATOMS BY MICROWAVE PLASMA CHEMICAL VAPOR DEPOSITION PROCESS .	KANAI, MASAHIRO
07302243	4908329	150	01/27/1989	PROCESS FOR THE FORMATION OF A FUNCTIONAL DEPOSITED FILM CONTAINING GROUPS II AND VI ATOMS BY MICROWAVE PLASMA CHEMICAL VAPOR DEPOSITION PROCESS	KANAI, MASAHIRO
07298219	4869931	150	01/17/1989	METHOD FOR FORMING DEPOSITED FILMS OF GROUP II-VI COMPOUNDS	KANAI, MASAHIRO
07275619	Not Issued	166	11/25/1988	DEVICE FOR FORMING A DEPOSITED FILM	KANAI, MASAHIRO
07236792	4888062	150	08/26/1988	PIN JUNCTION PHOTOVOLTAIC ELEMENT HAVING I-TYPE	KANAI, MASAHIRO

				SEMICONDUCTOR LAYER COMPRISING NON-SINGLE CRYSTAL MATERIAL CONTAINING AT LEAST ZN, SE AND H IN AN AMOUNT OF 1 TO 4 ATOMIC %	
07226819	5028488	150	08/01/1988	FUNCTIONAL ZNSE1-XTEX: H DEPOSITED FILM	KANAI , MASAHIRO
07222093	Not Issued	166	07/20/1988	PHOTOVOLTAIC ELEMENT WITH A SEMICONDUCTOR LAYER COMPRISING NON- SINGLE CRYSTAL MATERIAL CONTAINING AT LEAST ZN, SE AND H IN AN AMOUNT OF 1 TO 40 ATOMIC %	KANAI , MASAHIRO
07212096	Not Issued	166	06/27/1988	PROCESS FOR FORMING DEPOSITED FILM	KANAI , MASAHIRO
07113414	4772486	150	10/27/1987	PROCESS FOR FORMING A DEPOSITED FILM	KANAI , MASAHIRO
07015951	4800173	150	02/18/1987	PROCESS FOR PREPARING SI OR GE EPITAXIAL FILM USING FLUORINE OXIDANT	KANAI , MASAHIRO
07012367	Not Issued	166	02/09/1987	PROCESS FOR THE PRODUCTION OF FUNCTIONAL CRYSTALLINE FILM	KANAI , MASAHIRO
07003054	4868014	150	01/13/1987	METHOD FOR FORMING THIN FILM MULTI-LAYER STRUCTURE MEMBER	KANAI , MASAHIRO
07003048	Not Issued	166	01/13/1987	DEVICE FOR FORMING DEPOSITED FILM	KANAI , MASAHIRO
06947029	4771015	150	12/29/1986	METHOD FOR PRODUCING AN ELECTRONIC DEVICE HAVING A MULTI-LAYER STRUCTURE	KANAI , MASAHIRO
06946206	4772570	150	12/24/1986	METHOD FOR PRODUCING AN ELECTRONIC DEVICE HAVING A MULTI-LAYER STRUCTURE	KANAI , MASAHIRO
06945580	Not Issued	166	12/23/1986	DEVICE FOR FORMING A DEPOSITED FILM	KANAI , MASAHIRO
06944359	4830890	150	12/22/1986	METHOD FOR FORMING A DEPOSITED FILM FROM A GASEOUS SILANE COMPOUND HEATED ON A SUBSTRATE AND	KANAI , MASAHIRO

INTRODUCING AN ACTIVE SPECIES THEREWITH					
06943071	4728528	150	12/18/1986	PROCESS FOR FORMING DEPOSITED FILM	KANAI , MASAHIRO
06942806	Not Issued	166	12/22/1986	APPARATUS FOR FORMING DEPOSIT FILM	KANAI , MASAHIRO
06941425	Not Issued	166	12/15/1986	METHOD FOR FORMING DEPOSITED FILMS OF GROUP II-VI COMPOUNDS	KANAI , MASAHIRO
06939229	Not Issued	166	12/08/1986	PROCESS FOR FORMING DEPOSITED FILM	KANAI , MASAHIRO

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Your Search was:

Last Name = KANAI

First Name = MASAHIRO

Application#	Patent#	Status	Date Filed	Title	Inventor Name 51
09337557	6338872	150	06/22/1999	FILM FORMING METHOD	KANAI, MASAHIRO
09294367	Not Issued	161	04/20/1999	PROCESSING APPARATUS, EXHAUST PROCESSING PROCESS AND PLASMA PROCESSING	KANAI, MASAHIRO
09260044	6482668	150	03/02/1999	PROCESS FOR PRODUCING PHOTOVOLTAIC DEVICE	KANAI, MASAHIRO
09258208	6313430	150	02/26/1999	PLASMA PROCESSING APPARATUS AND PLASMA PROCESSING METHOD	KANAI, MASAHIRO
09257027	6530341	150	02/25/1999	DEPOSITION APPARATUS FOR MANUFACTURING THIN FILM	KANAI, MASAHIRO
09080922	6031198	150	05/19/1998	PLASMA PROCESSING METHOD AND APPARATUS	KANAI, MASAHIRO
09038708	6271055	150	03/09/1998	PROCESS FOR MANUFACTURING SEMICONDUCTOR ELEMENT USING NON- MONCRYSTALLINE SEMICONDUCTOR LAYERS OF FIRST AND SECOND CONDUCTIVITY TYPES AND AMORPHOUS AND MICROCRYSTALLINE I-TYPE SEMICONDUCTORS LAYERS	KANAI, MASAHIRO
09037825	6153823	150	03/11/1998	PHOTOELECTRIC CONVERSION ELEMENT HAVING A SURFACE MEMBER OR A PROTECTION MEMBER AND BUILDING MATERIAL USING THE SAME	KANAI, MASAHIRO

09021987	5928722	150	02/11/1998	METHOD OF TRANSFERRING BONDING AGENT AND TRANSFER APPARATUS	KANAI, MASAHIRO
08927413	6159763	150	09/10/1997	METHOD AND DEVICE FOR FORMING SEMICONDUCTOR THIN FILM, AND METHOD AND DEVICE FOR FORMING PHOTOVOLTAIC ELEMENT	KANAI, MASAHIRO
08844429	6096389	150	04/18/1997	METHOD AND APPARATUS FOR FORMING A DEPOSITED FILM USING A <u>MICROWAVE CVD PROCESS</u>	KANAI, MASAHIRO
08800512	6153013	150	02/14/1997	DEPOSITED-FILM-FORMING APPARATUS	KANAI, MASAHIRO
08782811	5927994	150	01/13/1997	METHOD FOR MANUFACTURING THIN FILM, AND DEPOSITION APPARATUS	KANAI, MASAHIRO
08773907	Not Issued	161	12/27/1996	INSTRUMENT FOR SIMPLIFIED IMMUNOASSAY AND SIMPLIFIED IMMUNOASSAY METHOD USING THE INSTRUMENT	KANAI, MASAHIRO
08768609	6350489	150	12/18/1996	DEPOSITED-FILM FORMING PROCESS AND DEPOSITED-FILM FORMING APPARATUS	KANAI, MASAHIRO
08754066	5968274	150	11/20/1996	CONTINUOUS FORMING METHOD FOR FUNCTIONAL DEPOSITED FILMS AND DEPOSITION APPARATUS	KANAI, MASAHIRO
08741352	5946587	150	10/29/1996	CONTINUOUS FORMING METHOD FOR FUNCTIONAL DEPOSITED FILMS	KANAI, MASAHIRO
08717629	5897332	150	09/23/1996	METHOD FOR MANUFACTURING PHOTOELECTRIC CONVERSION ELEMENT	KANAI, MASAHIRO
08704138	6273955	150	08/28/1996	FILM FORMING APPARATUS AND METHOD	KANAI, MASAHIRO
08697684	Not Issued	161	08/28/1996	PHOTOVOLTAIC CELL AND METHOD OF AND APPARATUS FOR ITS FABRICATION	KANAI, MASAHIRO
08617943	5766349	150	03/15/1996	TRANSFER APPARATUS FOR TRANSFERRING BONDING AGENT	KANAI, MASAHIRO

08610076	5919310	150	02/29/1996	CONTINUOUSLY FILM- FORMING APPARATUS PROVIDED WITH IMPROVED GAS GATE MEANS	KANAI, MASAHIRO
08528330	5629054	150	09/14/1995	METHOD FOR CONTINUOUSLY FORMING A FUNCTIONAL DEPOSIT FILM OF LARGE AREA BY MICRO- WAVE PLASMA CVD METHOD	KANAI, MASAHIRO
08523169	5589007	150	09/05/1995	PHOTOVOLTAIC ELEMENTS AND PROCESS AND APPARATUS FOR THEIR FORMATION	KANAI, MASAHIRO
08459485	5520740	150	06/02/1995	PROCESS FOR CONTINUOUSLY FORMING A LARGE AREA FUNCTIONAL DEPOSITED FILM BY MICROWAVE PCVD METHOD AND APPARATUS SUITABLE FOR PRACTICING THE SAME	KANAI, MASAHIRO
08450620	5714010	150	05/25/1995	PROCESS FOR CONTINUOUSLY FORMING A LARGE AREA FUNCTIONAL DEPOSITED FILM BY MICROWAVE PCVD METHOD AND AN APPARATUS SUITABLE FOR PRACTICING THE SAME	KANAI, MASAHIRO
08351949	5523126	150	12/08/1994	METHOD OF CONTINUOUSLY FORMING A LARGE AREA FUNCTIONAL DEPOSITED FILM BY MICROWAVE PCVD	KANAI, MASAHIRO
08334032	5468521	150	11/02/1994	METHOD FOR FORMING A PHOTOELECTRIC DEPOSITED FILM	KANAI, MASAHIRO
08262360	Not Issued	166	06/20/1994	METHOD AND APPARATUS FOR CONTINUOUSLY FORMING FUNCTIONAL DEPOSITED FILMS WITH A LARGE AREA BY A MICROWAVE PLASMA CVD METHOD	KANAI, MASAHIRO
08261655	5514217	150	06/07/1994	MICROWAVE PLASMA CVD APPARATUS WITH A DEPOSITION CHAMBER HAVING A	KANAI, MASAHIRO

Very large case ↓

				CIRCUMFERENTIAL WALL COMPRISING A CURVED MOVING SUBSTRATE WEB AND A MICROWAVE APPLICATOR MEANS HAVING A SPECIFIC DIELECTRIC MEMBER ON THE EXTERIOR THEREOF	
08255815	Not Issued	166	06/07/1994	METHOD FOR CONTINUOUSLY FORMING A FUNCTIONAL DEPOSIT FILM OF LARGE AREA BY MICROWAVE PLASMA CVD METHOD	KANAI, MASAHIRO
08220575	5976257	150	03/31/1994	METHOD AND APPARATUS FOR CONTINUOUSLY FORMING A LARGE AREA FUNCTIONAL DEPOSITED FILM BY MEANS OF MICROWAVE PLASMA CVD PROCESS	KANAI, MASAHIRO
08218834	Not Issued	166	03/28/1994	PROCESS FOR FORMING A DEPOSITED FILM USING A GAS PHASE METHOD INVOLVING AT LEAST ONE ACTIVATED COMPOUND	KANAI, MASAHIRO
08187550	Not Issued	166	01/28/1994	PHOTOVOLTAIC ELEMENTS AND PROCESS AND APPARATUS FOR THEIR FORMATION	KANAI, MASAHIRO
08181478	Not Issued	166	01/14/1994	METHOD OF CONTINUOUSLY FORMING A LARGE AREA FUNCTIONAL DEPOSITED FILM BY MICROWAVE PCVD AND APPARATUS FOR THE SAME	KANAI, MASAHIRO
08091729	Not Issued	166	07/15/1993	METHOD FOR CONTINUOUSLY FORMING A FUNCTIONAL DEPOSIT FILM OF LARGE AREA BY MICROWAVE PLASMA CVD METHOD	KANAI, MASAHIRO
07994174	Not Issued	166	12/18/1992	METHOD AND APPARATUS FOR CONTINUOUSLY FORMING FUNCTIONAL DEPOSITED FILMS WITH A LARGE AREA BY A MICROWAVE PLASMA CVD	KANAI, MASAHIRO

				METHOD		
07967238	Not Issued	166	10/27/1992	DEPOSITED FILM FORMING METHOD AND DEPOSITED FILM FORMING APPARATUS	KANAI, MASAHIRO	
07943991	5510151	150	09/11/1992	CONTINUOUS FILM-FORMING PROCESS USING MICROWAVE ENERGY IN A MOVING SUBSTRATE WEB FUNCTIONING AS A SUBSTRATE AND A PLAMA GENERATING SPACE	KANAI, MASAHIRO	
07690313	Not Issued	166	04/25/1991	PROCESS FOR FORMING DEPOSITED FILM	KANAI, MASAHIRO	
07625021	Not Issued	166	12/10/1990	PHOTOVOLTAIC ELEMENT OF JUNCTION TYPE WITH AN ORGANIC SEMICONDUCTOR LAYER FORMED OF A POLYSILANE COMPOUND	KANAI, MASAHIRO	
07317653	4971832	150	03/01/1989	HR-CVD PROCESS FOR THE FORMATION OF A FUNCTIONAL DEPOSITED FILM ON A SUBSTRATE WITH APPLICATION OF A VOLTAGE IN THE RANGE OF -5 TO -100 V	KANAI, MASAHIRO	
07089758	Not Issued	166	08/27/1987	PROCESS AND APPARATUS FOR FORMING A DEPOSITED FILM	KANAI, MASAHIRO	
07061003	4726963	150	06/09/1987	PROCESS FOR FORMING DEPOSITED FILM	KANAI, MASAHIRO	
07012367	Not Issued	166	02/09/1987	PROCESS FOR THE PRODUCTION OF FUNCTIONAL CRYSTALLINE FILM	KANAI, MASAHIRO	
06739867	4705730	150	05/31/1985	LIGHT-RECEIVING MEMBER	KANAI, MASAHIRO	
06726768	4705732	150	04/24/1985	MEMBER HAVING SUBSTRATE WITH PROJECTING PORTIONS AT SURFACE AND LIGHT RECEIVING LAYER OF AMORPHOUS SILICON	KANAI, MASAHIRO	
06720011	4701393	150	04/04/1985	MEMBER WITH LIGHT RECEIVING LAYER OF A-SI (GE) AND A-SI AND HAVING PLURALITY OF NON-	KANAI, MASAHIRO	

				PARALLEL INTERFACES	
06719980	4701392	150	04/04/1985	MEMBER HAVING LIGHT RECEIVING LAYER WITH NONPARALLEL INTERFACES AND ANTIREFLECTION LAYER	KANAI, MASAHIRO
06717821	4720443	150	03/29/1985	MEMBER HAVING LIGHT RECEIVING LAYER WITH NONPARALLEL INTERFACES	KANAI, MASAHIRO
06699868	4650736	150	02/08/1985	LIGHT RECEIVING MEMBER HAVING PHOTOSENSITIVE LAYER WITH NON-PARALLEL INTERFACES	KANAI, MASAHIRO

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Your Search was:

Last Name = KANAI

First Name = MASAHIRO

Application#	Patent#	Status	Date Filed	Title	Inventor Name 42
09439609	6602347	150	11/12/1999	APPARATUS AND METHOD FOR PROCESSING A SUBSTRATE	KANAI, MASAHIRO
09425169	6312411	150	10/22/1999	FLUID SUPPLYING APPARATUS <i>? liquid?</i> <i>? gas?</i>	KANAI, MASAHIRO
09419115	6397775	150	10/15/1999	DEPOSITED FILM FORMING SYSTEM AND PROCESS	KANAI, MASAHIRO
09363825	6287943	150	07/30/1999	DEPOSITION OF SEMICONDUCTOR LAYER BY PLASMA PROCESS	KANAI, MASAHIRO
09358930	6261862	150	07/23/1999	PROCESS FOR PRODUCING PHOTOVOLTAIC ELEMENT	KANAI, MASAHIRO
09110124	6223684	150	07/06/1998	FILM DEPOSITION APPARATUS	KANAI, MASAHIRO
09076238	6093290	150	05/12/1998	METHOD OF GENERATING A RECIPROCATING PLURALITY OF MAGNETIC FLUXES ON A TARGET	KANAI, MASAHIRO
08814081	6113732	150	03/10/1997	DEPOSIT FILM FORMING APPARATUS	KANAI, MASAHIRO
08359817	Not Issued	164	12/20/1994	PHOTOVOLTAIC CELL AND METHOD OF AND APPARATUS FOR ITS FABRICATION	KANAI, MASAHIRO
08305285	5482557	150	09/14/1994	DEVICE FOR FORMING DEPOSITED FILM	KANAI, MASAHIRO
08302221	Not Issued	166	09/07/1994	PROCESS FOR CONTINUOUSLY FORMING A LARGE AREA SUITABLE FOR PRACTICING THE SAME	KANAI, MASAHIRO
08295487	5397395	150	08/25/1994	METHOD OF CONTINUOUSLY FORMING A LARGE AREA FUNCTIONAL DEPOSITED	KANAI, MASAHIRO

No

				FILM BY MICROWAVE PCVD AND APPARATUS FOR THE SAME	
08271331	5559464	150	07/06/1994	SIGNAL VOLTAGE LEVEL CONVERSION CIRCUIT AND OUTPUT BUFFER CIRCUIT	KANAI , MASAHIRO
08073976	5391232	150	06/08/1993	DEVICE FOR FORMING A DEPOSITED FILM	KANAI , MASAHIRO
08070476	Not Issued	166	10/14/1993	CONTINUOUSLY FILM-FORMING APPARATUS PROVIDED WITH IMPROVED GAS GATE MEANS	KANAI , MASAHIRO
08041511	Not Issued	166	04/01/1993	PROCESS FOR FORMING DEPOSITED FILM	KANAI , MASAHIRO
07999543	Not Issued	166	12/31/1992	MICROWAVE PLASMA VCD APPARATUS WITH A DEPOSITION CHAMBER HAVING A CIRCUMFERENTIAL WALL COMPRISING A CURVED MOVING SUBSTRATE WEB AND A MICROWAVE APPLICATOR MEANS HAVING A SPECIFIC DIELECTRIC MEMBER ON THE EXTERIOR THEREOF	KANAI , MASAHIRO
07800456	5296036	150	11/27/1991	APPARATUS FOR CONTINUOUSLY FORMING A LARGE AREA FUNCTIONAL DEPOSIT FILM INCLUDING MICROWAVE TRANSMISSIVE MEMBER TRANSFER MEANS	KANAI , MASAHIRO
07799900	5192717	150	12/02/1991	PROCESS FOR THE FORMATION OF A POLYCRYSTALLINE SEMICONDUCTOR FILM BY MICROWAVE PLASMA CHEMICAL VAPOR DEPOSITION METHOD	KANAI , MASAHIRO
07769163	Not Issued	166	10/11/1991	DEVICE FOR FORMING A DEPOSITED FILM	KANAI , MASAHIRO
07744820	Not Issued	166	08/12/1991	PROCESS FOR THE FORMATION OF A FUNCTIONAL DEPOSITED FILM BY HYDROGEN RADICAL-ASSISTED CVD METHOD UTILIZING	KANAI , MASAHIRO

				HYDROGEN GAS PLASMA IN SHEET-LIKE STATE			
07469808	5294285	150	01/22/1990	PROCESS FOR THE PRODUCTION OF FUNCTIONAL CRYSTALLINE FILM		KANAI , MASAHIRO	
07467537	5007971	150	01/19/1990	PIN HETEROJUNCTION PHOTOVOLTAIC ELEMENTS WITH POLYCRYSTAL BP(H,F) SEMICONDUCTOR FILM		KANAI , MASAHIRO	
07467523	5024706	150	01/19/1990	PIN HETEROJUNCTION PHOTOVOLTAIC ELEMENTS WITH POLYCRYSTAL A1P (H,F) SEMICONDUCTOR FILM		KANAI , MASAHIRO	
07442511	4951602	150	11/28/1989	MICROWAVE PLASMA CHEMICAL VAPOR DEPOSITION APPARATUS FOR CONTINUOUSLY PREPARING SEMICONDUCTOR DEVICES		KANAI , MASAHIRO	
07441224	Not Issued	166	11/27/1989	DEVICE FOR FORMING DEPOSITED FILM		KANAI , MASAHIRO	
07439539	Not Issued	166	11/21/1989	PROCESS FOR THE FORMATION OF A FUNCTIONAL DEPOSITED FILM BY HYDROGEN RADICAL-ASSISTED CVD METHOD UTILIZING HYDROGEN GAS PLASMA IN SHEET-LIKE STATE		KANAI , MASAHIRO	
06831413	4818563	150	02/20/1986	PROCESS FOR FORMING DEPOSITED FILM		KANAI , MASAHIRO	
06831412	Not Issued	166	02/20/1986	PROCESS FOR FORMING DEPOSITED FILM		KANAI , MASAHIRO	
06831411	4853251	150	02/20/1986	PROCESS FOR FORMING DEPOSITED FILM INCLUDING CARBON AS A CONSTITUENT ELEMENT		KANAI , MASAHIRO	
06829929	Not Issued	166	02/18/1986	PROCESS FOR FORMING DEPOSITED FILM		KANAI , MASAHIRO	
06829928	Not Issued	166	02/18/1986	PROCESS FOR FORMING DEPOSITED FILM		KANAI , MASAHIRO	
06829791	Not Issued	166	02/14/1986	PROCESS FOR FORMING A DEPOSITED FILM		KANAI , MASAHIRO	
06829072	4717586	150	02/13/1986	PROCESS FOR FORMING		KANAI ,	

				DEPOSITED FILM	MASAHIRO
06828543	Not Issued	166	02/12/1986	PROCESS FOR FORMING DEPOSITED FILM	KANAI , MASAHIRO
06826898	4717585	150	02/06/1986	PROCESS FOR FORMING DEPOSITED FILM	KANAI , MASAHIRO
06815129	4661427	150	12/30/1985	AMORPHOUS SILICON PHOTOCONDUCTIVE MEMBER WITH REDUCED SPIN DENSITY IN SURFACE LAYER	KANAI , MASAHIRO
06786970	4678733	150	10/11/1985	MEMBER HAVING LIGHT RECEIVING LAYER OF A-SI:GE (C, N, O) A-SI/SURFACE ANTIREFLECTION LAYER WITH NONPARALLEL INTERFACES	KANAI , MASAHIRO
06753048	4696883	150	07/08/1985	MEMBER HAVING LIGHT RECEIVING LAYER WITH SMOOTHLY CONNECTED NON- PARALLEL INTERFACES AND SURFACE REFLECTIVE LAYER	KANAI , MASAHIRO
06741300	4705735	150	06/04/1985	MEMBER HAVING SUBSTRATE WITH PROTRUDING SURFACE PORTIONS AND LIGHT RECEIVING LAYER WITH AMORPHOUS SILICON MATRIX	KANAI , MASAHIRO
06740714	4705734	150	06/03/1985	MEMBER HAVING SUBSTRATE WITH IRREGULAR SURFACE AND LIGHT RECEIVING LAYER OF AMORPHOUS SILICON	KANAI , MASAHIRO
06739867	4705730	150	05/31/1985	LIGHT-RECEIVING MEMBER	KANAI , MASAHIRO

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1	L1	18	("5126169" "5468521" "5482557" "5575855" "6031198" "6153013" "6159300" "6223684").PN.	USPAT; US_PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/05/18 12:00
2	L2	24352	((216/67-71,94) or (427/446-456,488- 491,523-531,533-5 40,562-564,569-58 0) or (204/192.12-192.3 8,298.07,298.09,2 98.33,298.41) or (118/723MW-723IR)).CCLS.	USPAT; US_PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/05/18 12:10
3	L3	2995	(134/1-1.3).CCLS.	USPAT; US_PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/05/18 12:10
4	L4	26971	2 or 3	USPAT; US_PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/05/18 12:14
5	L5	5939	588/\$.ccls.	USPAT; US_PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/05/18 12:15
6	L6	26	4 and 5	USPAT; US_PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/05/18 12:16
7	L7	170082	(waste exhaust byproduct "by-product" "by product" unreacted adj2 (gas reagent precursor))near3 (treat\$6 process\$4)	USPAT; US_PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/05/18 12:29

FAST Search - 09/822,191

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8	L8	1153	4 and 7	USPAT; US_PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/05/18 12:22
9	L9	1171	6 or 8	USPAT; US_PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/05/18 12:23
10	L10	8	6 and 8	USPAT; US_PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/05/18 12:23
11	L11	18	6 not 8	USPAT; US_PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/05/18 12:24
12	L12	862	8 and (chromium Cr molybdenum Mo.m/c. tungsten W.u/c. V.u/c. vanadium niobium Nb tantalum Ta.m/c. titanium Ti.m/c. zirconium Zr Ha.m/c. hafnium)	USPAT; US_PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/05/18 12:28
13	L13	149	8 and((waste exhaust byproduct "by-product" "by product" unreacted adj2 (gas reagent precursor)) near3 (treat\$6 process\$4)) same (chromium Cr molybdenum Mo.m/c. tungsten W.u/c. V.u/c. vanadium niobium Nb tantalum Ta.m/c. titanium Ti.m/c. zirconium Zr Ha.m/c. hafnium)	USPAT; US_PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/05/18 12:31

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14	L14	147	13 not 6	USPAT; US-PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/05/18 12:31
15	L15	2	13 and 6	USPAT; US-PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/05/18 12:31

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PALM INTRANET**Inventor Name Search Result**

Your Search was:

Last Name = SHISHIDO

First Name = TAKESHI

Application#	Patent#	Status	Date Filed	Title	Inventor Name 14
10733452	Not Issued	030	12/12/2003 427/569	DEPOSITED-FILM FORMATION APPARATUS, AND DEPOSITED-FILM FORMATION PROCESS	SHISHIDO, TAKESHI <i>JFW - Mine</i>
10656131	Not Issued	020	09/08/2003 118/123 E 20040145504	DEPOSITED FILM FORMING APPARATUS AND DEPOSITED FILM FORMING METHOD	SHISHIDO, TAKESHI <i>JFW</i>
10650763	Not Issued	030	08/29/2003 427/569 20040133261	APPARATUS AND METHOD FOR FORMING DEPOSITED FILM	SHISHIDO, TAKESHI <i>JFW - T-Mek</i>
10472679	Not Issued	030	09/18/2003	STABLE ASTAXANTHIN-CONTAINING POWDERY COMPOSITIONS AND PROCESS FOR PRODUCING THE SAME	SHISHIDO, TAKESHI
10457513	Not Issued	030	06/10/2003	APPARATUS AND PROCESS FOR FORMING DEPOSITED FILM	SHISHIDO, TAKESHI
10101859	Not Issued	160	03/21/2002	METHOD OF FORMING SILICON-BASED THIN FILM, SILICON-BASED THIN FILM, AND PHOTOVOLTAIC ELEMENT	SHISHIDO, TAKESHI
09822191	Not Issued	071	04/02/2001	EXHAUST PROCESSING METHOD, PLASMA PROCESSING METHOD AND PLASMA PROCESSING APPARATUS	SHISHIDO, TAKESHI
09772988	6638359	150	01/31/2001	DEPOSITED FILM FORMING APPARATUS AND DEPOSITED FILM FORMING METHOD	SHISHIDO, TAKESHI
09771650	6470823	150	01/30/2001	APPARATUS AND METHOD	SHISHIDO,

				FOR FORMING A DEPOSITED FILM BY MEANS OF PLASMA CVD	TAKESHI
09769328 2001002296	Not Issued	082 163 156/34543	01/26/2001	DEPOSITED-FILM FORMATION APPARATUS, AND DEPOSITED-FILM FORMATION PROCESS	SHISHIDO, TAKESHI <i>FFW</i>
09767856	6632284	150	01/24/2001	APPARATUS AND METHOD FOR FORMING DEPOSITED FILM	SHISHIDO, TAKESHI
09727440	6526910	150	12/04/2000	APPARATUS AND METHOD FOR FORMING A DEPOSITED FILM BY MEANS OF PLASMA CVD	SHISHIDO, TAKESHI
09509996	6562372	150	04/05/2000	TOCOTRIENOL-CONTAINING POWDER, A PROCESS FOR PREPARING IT AND A TABLET COMPRISING COMPRESSED SAID POWDER INTO A TABLET FORM	SHISHIDO, TAKESHI
08958765	Not Issued	161	10/26/1997	APPARATUS FOR STORING AND SEARCHING INFORMATION RECORDING DISKS AND APPARATUS FOR RECORDING AND/OR REPRODUCING THE DISKS APPLYING THE ABOVE	SHISHIDO , TAKESHI

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Your Search was:

Last Name = OKABE

First Name = SHOTARO

Application#	Patent#	Status	Date Filed	Title	Inventor Name 46
10776173	Not Issued	020 2812	02/12/2004 438/—	PROCESSING APPARATUS, EXHAUST PROCESSING PROCESS AND PLASMA PROCESSING PROCESS	OKABE, SHOTARO <i>JFW</i>
10625041	Not Issued	030 1743	07/23/2003 18/119	APPARATUS FOR MANUFACTURING PHOTOVOLTAIC ELEMENTS	OKABE, SHOTARO <i>JFW</i>
10457513 <i>20040011296</i>	Not Issued	030 1762	06/10/2003 428/247	APPARATUS AND PROCESS FOR FORMING DEPOSITED FILM	OKABE, SHOTARO <i>JFW</i> - T. Noda
10238789 <i>20030022514</i>	Not Issued	020 1762	09/11/2002 18/112 unexam.	PRODUCTION APPARATUS OF SEMICONDUCTOR LAYER EMPLOYING DC BIAS AND VHF POWER	OKABE, SHOTARO <i>JFW</i>
10113675 <i>20030104664</i>	Not Issued <i>Allowed</i>	092 2513	04/02/2002 438/485	PROCESS FOR FORMING A SILICON-BASED FILM ON A SUBSTRATE USING A TEMPERATURE GRADIENT ACROSS THE SUBSTRATE AXIS	OKABE, SHOTARO <i>JFW</i>
10101859 ✓	Not Issued	160 <i>chr</i>	03/21/2002	METHOD OF FORMING SILICON-BASED THIN FILM, SILICON-BASED THIN FILM, AND PHOTOVOLTAIC ELEMENT	OKABE, SHOTARO
10092617 <i>20030025777</i>	Not Issued <i>Allowed</i>	093 1775	03/08/2002 48/446	SEMICONDUCTOR ELEMENT, AND METHOD OF FORMING SILICON-BASED FILM	OKABE, SHOTARO <i>JFW</i>
10085102 ✓	Not Issued	161 <i>chr</i>	03/01/2002	METHOD OF MANUFACTURING PHOTOVOLTAIC ELEMENT AND APPARATUS THEREFOR	OKABE, SHOTARO
09912343	6472296	150	07/26/2001	FABRICATION OF PHOTOVOLTAIC CELL BY <i>plasma</i>	OKABE, SHOTARO

PLASMA PROCESS					
09911172	6495392	150	07/23/2001	PROCESS FOR PRODUCING A SEMICONDUCTOR DEVICE	OKABE, SHOTARO
09822191	Not Issued	071	04/02/2001	EXHAUST PROCESSING METHOD, PLASMA PROCESSING METHOD AND PLASMA PROCESSING APPARATUS	OKABE, SHOTARO
09797566 20010639924	Not Issued	071 1703 119/323	03/05/2001	APPARATUS FOR FORMING DEPOSITED FILM	OKABE, SHOTARO <i>JFW</i>
09678299	Not Issued	161	10/03/2000	METHOD AND DEVICE FOR FORMING SEMICONDUCTOR THIN FILM AND DEVICE FOR FORMING PHOTOVOLTAIC ELEMENT	OKABE, SHOTARO
09664219	6368944	150	09/18/2000	METHOD OF MANUFACTURING PHOTOVOLTAIC ELEMENT AND APPARATUS THEREFOR	OKABE, SHOTARO
09645036	Not Issued	164	08/24/2000	PROCESS FOR PRODUCING A SEMICONDUCTOR DEVICE	OKABE, SHOTARO
09594563	6399411	150	06/15/2000	METHOD FOR FORMING NON-SINGLE-CRYSTAL SEMICONDUCTOR THIN FILM, AND METHOD FOR PRODUCING PHOTOVOLTAIC DEVICE	OKABE, SHOTARO
09578906	6436797	150	05/26/2000	APPARATUS AND METHOD FOR FORMING A DEPOSITED FILM ON A SUBSTRATE	OKABE, SHOTARO
09363825	6287943	150	07/30/1999	DEPOSITION OF SEMICONDUCTOR LAYER BY PLASMA PROCESS	OKABE, SHOTARO
09294367	Not Issued	161	04/20/1999	PROCESSING APPARATUS, EXHAUST PROCESSING PROCESS AND PLASMA PROCESSING	OKABE, SHOTARO
09258208	6313430	150	02/26/1999	PLASMA PROCESSING APPARATUS AND PLASMA PROCESSING METHOD	OKABE, SHOTARO
09257027	6530341	150	02/25/1999	DEPOSITION APPARATUS FOR MANUFACTURING THIN FILM	OKABE, SHOTARO
09038708	6271055	150	03/09/1998	PROCESS FOR MANUFACTURING SEMICONDUCTOR ELEMENT	OKABE, SHOTARO

				USING NON-MONCRYSTALLINE SEMICONDUCTOR LAYERS OF FIRST AND SECOND CONDUCTIVITY TYPES AND AMORPHOUS AND MICROCRYSTALLINE I-TYPE SEMICONDUCTORS LAYERS	
08990915	6159300	150	12/15/1997	APPARATUS FOR FORMING NON-SINGLE-CRYSTAL SEMICONDUCTOR THIN FILM, METHOD FOR FORMING NON-SINGLE-CRYSTAL SEMICONDUCTOR THIN FILM, AND METHOD FOR PRODUCING PHOTOVOLTAIC DEVICE	OKABE, SHOTARO
08927413	6159763	150	09/10/1997	METHOD AND DEVICE FOR FORMING SEMICONDUCTOR THIN FILM, AND METHOD AND DEVICE FOR FORMING PHOTOVOLTAIC ELEMENT	OKABE, SHOTARO
08923259	6162988	150	09/04/1997	PHOTOVOLTAIC ELEMENT	OKABE, SHOTARO
08800512	6153013	150	02/14/1997	DEPOSITED-FILM-FORMING APPARATUS	OKABE, SHOTARO
08782811	5927994	150	01/13/1997 ?	METHOD FOR MANUFACTURING THIN FILM, AND DEPOSITION APPARATUS	OKABE, SHOTARO
08754066	5968274	150	11/20/1996 ?	CONTINUOUS FORMING METHOD FOR FUNCTIONAL DEPOSITED FILMS AND DEPOSITION APPARATUS	OKABE, SHOTARO
08741352	5946587	150	10/29/1996 ?	CONTINUOUS FORMING METHOD FOR FUNCTIONAL DEPOSITED FILMS	OKABE, SHOTARO
08717629	5897332	150	09/23/1996 ?	METHOD FOR MANUFACTURING PHOTOELECTRIC CONVERSION ELEMENT	OKABE, SHOTARO
08697783	5769963	150	08/30/1996	PHOTOVOLTAIC DEVICE	OKABE, SHOTARO
08697684	Not Issued	161	08/28/1996	PHOTOVOLTAIC CELL AND METHOD OF AND APPARATUS FOR ITS FABRICATION	OKABE, SHOTARO

08657066	5720826	150	05/29/1996	PHOTOVOLTAIC ELEMENT AND FABRICATION PROCESS THEREOF	OKABE , SHOTARO
08610076	5919310	150	02/29/1996	CONTINUOUSLY FILM-FORMING APPARATUS PROVIDED WITH IMPROVED GAS GATE MEANS	OKABE , SHOTARO
08523169	5589007	150	09/05/1995	PHOTOVOLTAIC ELEMENTS AND PROCESS AND APPARATUS FOR THEIR FORMATION	OKABE , SHOTARO
08416468	Not Issued	166	04/04/1995	CONTINUOUS FORMING METHOD FOR FUNCTIONAL DEPOSITED FILMS AND DEPOSITION THEREOF	OKABE , SHOTARO
08404616	Not Issued	166	03/15/1995	CONTINUOUS FORMING METHOD FOR FUNCTIONAL DEPOSITED FILMS AND DEPOSITION APPARATUS	OKABE , SHOTARO
08359817	Not Issued	164	12/20/1994	PHOTOVOLTAIC CELL AND METHOD OF AND APPARATUS FOR ITS FABRICATION	OKABE , SHOTARO
08187550	Not Issued	166	01/28/1994	PHOTOVOLTAIC ELEMENTS AND PROCESS AND APPARATUS FOR THEIR FORMATION	OKABE , SHOTARO
08101018	Not Issued	166	08/03/1993	CONTINUOUS FORMING METHOD FOR FUNCTIONAL DEPOSITED FILMS AND DEPOSITION APPARATUS	OKABE , SHOTARO
08070476	Not Issued	161	10/14/1993	CONTINUOUSLY FILM-FORMING APPARATUS PROVIDED WITH IMPROVED GAS GATE MEANS	OKABE , SHOTARO
07208214	4913928	150	06/17/1988	MICROWAVE PLASMA CHEMICAL VAPOR DEPOSITION APPARATUS WITH MAGNET ON WAVEGUIDE	OKABE , SHOTARO
06731334	4599971	150	05/06/1985	VAPOR DEPOSITION FILM FORMING APPARATUS	OKABE , SHOTARO
06650164	Not Issued	166	09/13/1984	PLASMA VAPOR DEPOSITION FILM FORMING APPARATUS	OKABE , SHOTARO
06647608	4545328	150	09/06/1984	PLASMA VAPOR DEPOSITION FILM FORMING APPARATUS	OKABE , SHOTARO

06647607	(4539934)	150	09/06/1984	PLASMA VAPOR DEPOSITION FILM FORMING APPARATUS	OKABE , SHOTARO
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2	L2	1700 82	(waste exhaust byproduct "by-product" "by product" unreacted adj2 (gas reagent precursor))near3 (treat\$6 process\$4)	USPAT; US_PGPUB; ; EPO; JPO; DERWENT; IBM_TDB	2004/05/19 11:45
3	L3	7	1 and 2	USPAT; US_PGPUB; ; EPO; JPO; DERWENT; IBM_TDB	2004/05/19 11:44

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5	L5	7	1 and (waste exhaust byproduct "by-product" "by product" unreacted adj2 (gas reagent precursor)) near3 (treat\$6 process\$4)	USPAT; US-PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/05/19 12:13
6	L6	80	1 and (waste exhaust byproduct "by-product" "by product" unreacted adj2 (gas reagent precursor)) not 3	USPAT; US-PGPUB ; EPO; JPO; DERWENT; IBM_TDB	2004/05/19 12:14